Supplementary Information

## Sub-10 nm Ta Channel Responsible for Superior Performance of a HfO<sub>2</sub> Memristor

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**Figure S1.** Typical I-V curves for the electroforming process from 10 randomly chosen Ta/HfO<sub>2</sub>/Pt devices. The forming voltages are around 2.2 V. After the forming process, the devices stay at ON state.



**Figure S2.** (a) Distributions of both LRS and HRS resistances from 50 consecutive DC sweeps. The window is kept > 10 X. (d) Statistics of SET and RESET voltages, which are normally distributed around 0.65 V and -1.1 V separately. Device size:  $10 \times 10 \ \mu m^2$ .



**Figure S3.** Retention measurements of the device at (a) HRS at 250 °C, (b) HRS at 275 °C, (c) LRS and HRS at 300 °C, (d) HRS at 325 °C and (e) HRS at 350 °C. The failure time for the HRS are  $2.7 \times 10^5$ ,  $7.5 \times 10^4$ ,  $1.4 \times 10^4$ ,  $2.7 \times 10^3$ , and  $1.3 \times 10^3$  s, respectively.



**Figure S4.** HAADF-STEM image and core-loss EELS mapping of an incomplete conduction channel. (a) HAADF-STEM image of an incomplete conduction channel. The EELS mapping results for (b) O, (c) Hf, (d) combination of Hf and Hf+Ta suggest the incomplete conduction channel is also Ta-rich and O-deficient.



**Figure S5.** STEM-EELS mapping of the conduction channel area. (a) HAADF-STEM image of the mapped region generated during mapping. (b) The EELS mapping result for O, clearly shows the conduction channel region is oxygen-deficient. The EELS mapping results for (c) Hf, (d) Hf + Ta, (e) combination of Hf and Hf + Ta, and (f) Pt indicate the conduction channel contains more Ta, which is consistent with the brighter intensity of the conduction channel in (a).